

FORMFACTOR
WAFAER-LEVEL. INTEGRATED.

High Parallelism Memory Test Advances based on MicroSpring™ Contact Technology

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Introduction to FormFactor

FormFactor Mission

100 mm Four Touchdown Probe Solution

- Cost of Ownership

- Specifications

- Performance

 - Electrical

 - Scrub alignment over temperature

 - MicroSpring™ array durability

Summary and Conclusions

Introduction to FormFactor

FormFactor

Established 1993

Livermore, CA

325 Employees

WaferProbeTM Probe Card Products

PH50, PH75 and new PH100

T1/T2.1 MicroSpringTM contact technology

High parallelism memory and C4 probing

FormFactor Mission

Reduce the cost of test through:

- Increased parallelism
- Improved productivity
- Reduced maintenance and cleaning

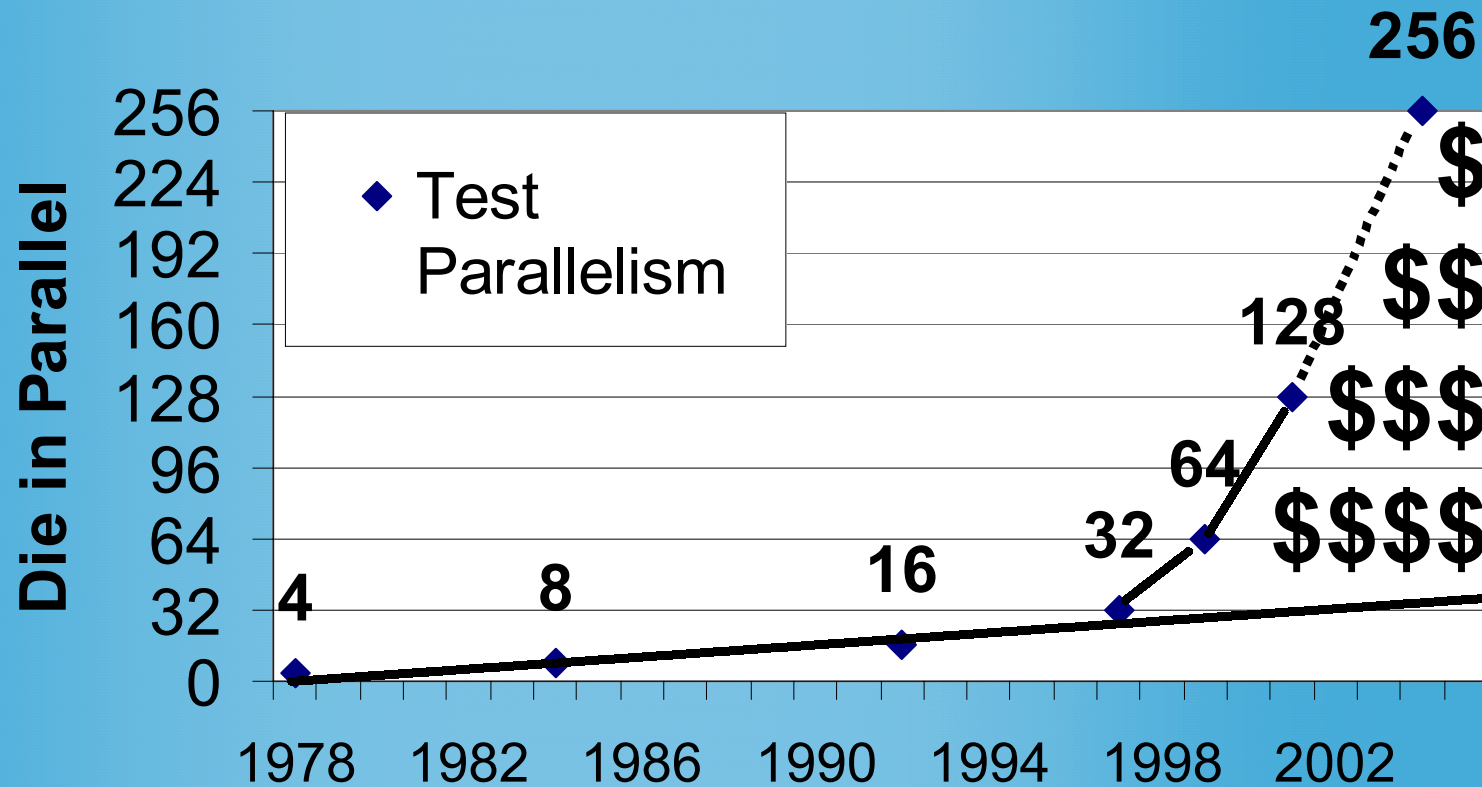
Meet new technology needs:

- Reduced pad size and pitch
- Improved electrical and mechanical performance
- Support new tester platforms

Extend technology developed for DRAM to provide solutions for FLASH and logic probing

Trends in High Parallelism Probing

Current and Historic Trends



Test Cost of Ownership Analysis

8" Virtual FAB - 25,000 wafer starts per month

Product - 128M SDRAM

- Good Die Value = \$4
- Die Size = 50mm²

Test time increases 15% per 2x test parallelism

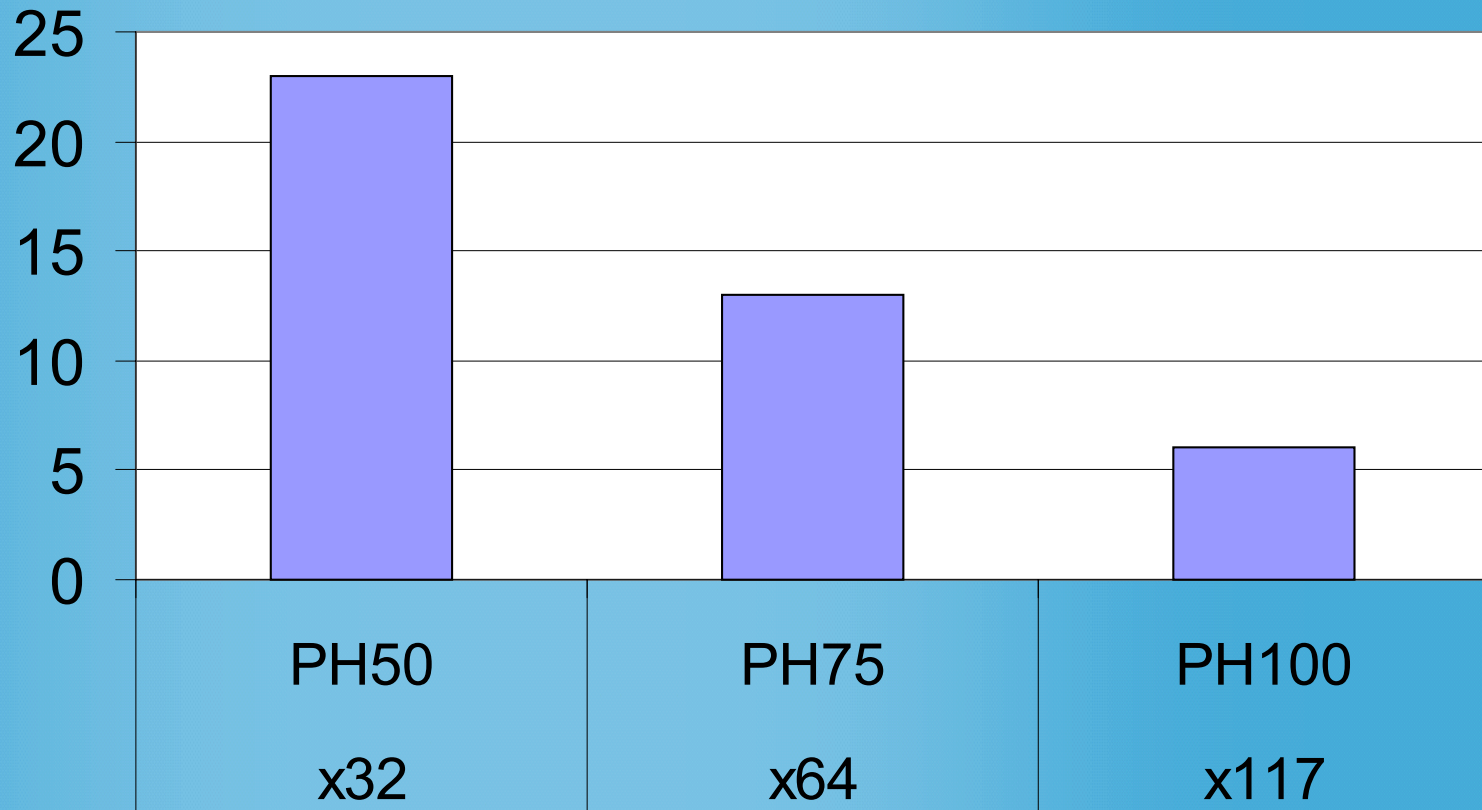
Compare the following situations:

Test Parallelism	32 DUT	64 DUT	117 DUT
Tester Cost	\$1.8M	\$2.2M	\$3.5M

High Parallelism Probing

- Reduces Touchdowns required

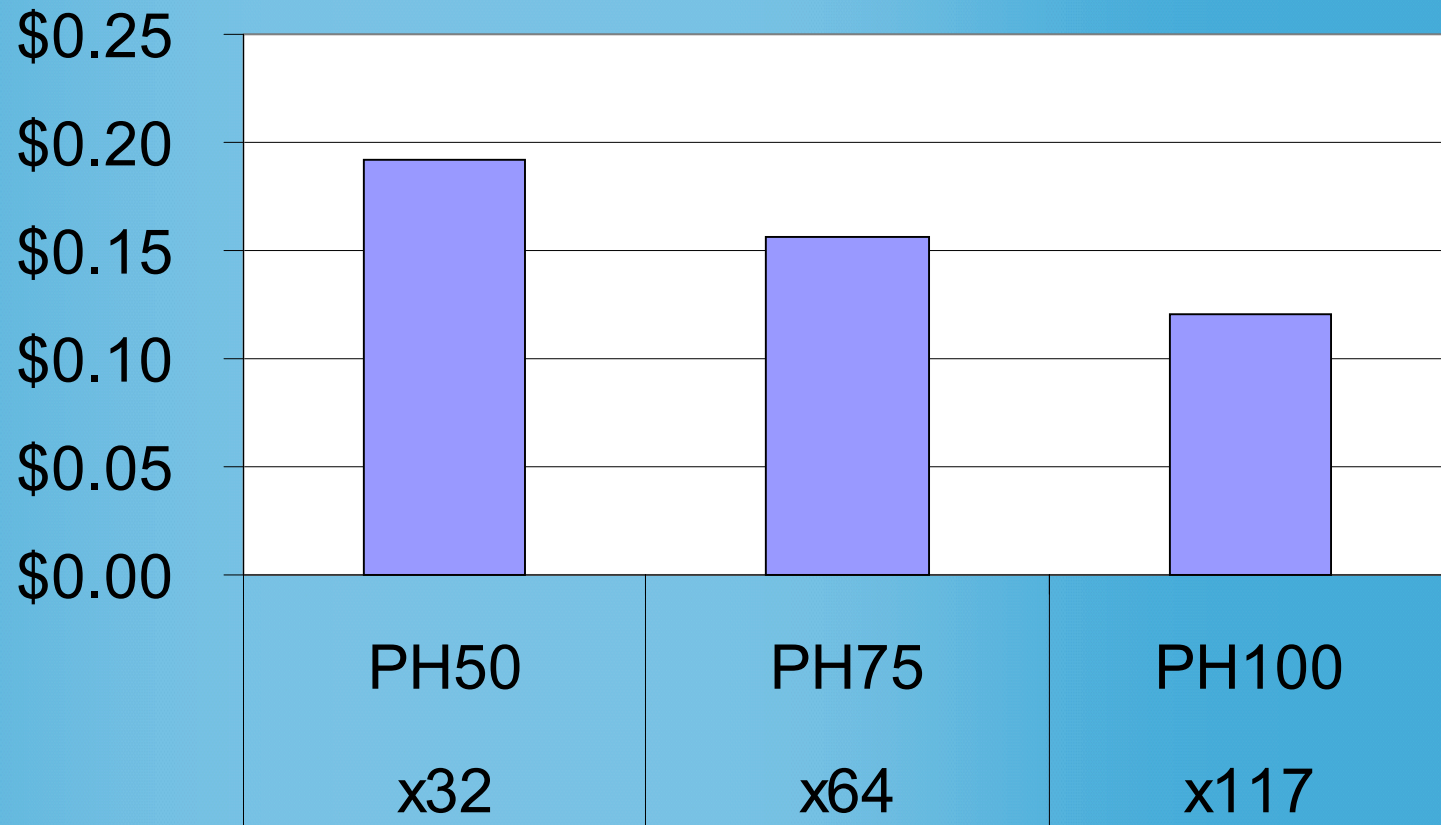
Number of Touchdowns



High Parallelism Probing

- Reduces Test Cost per DUT

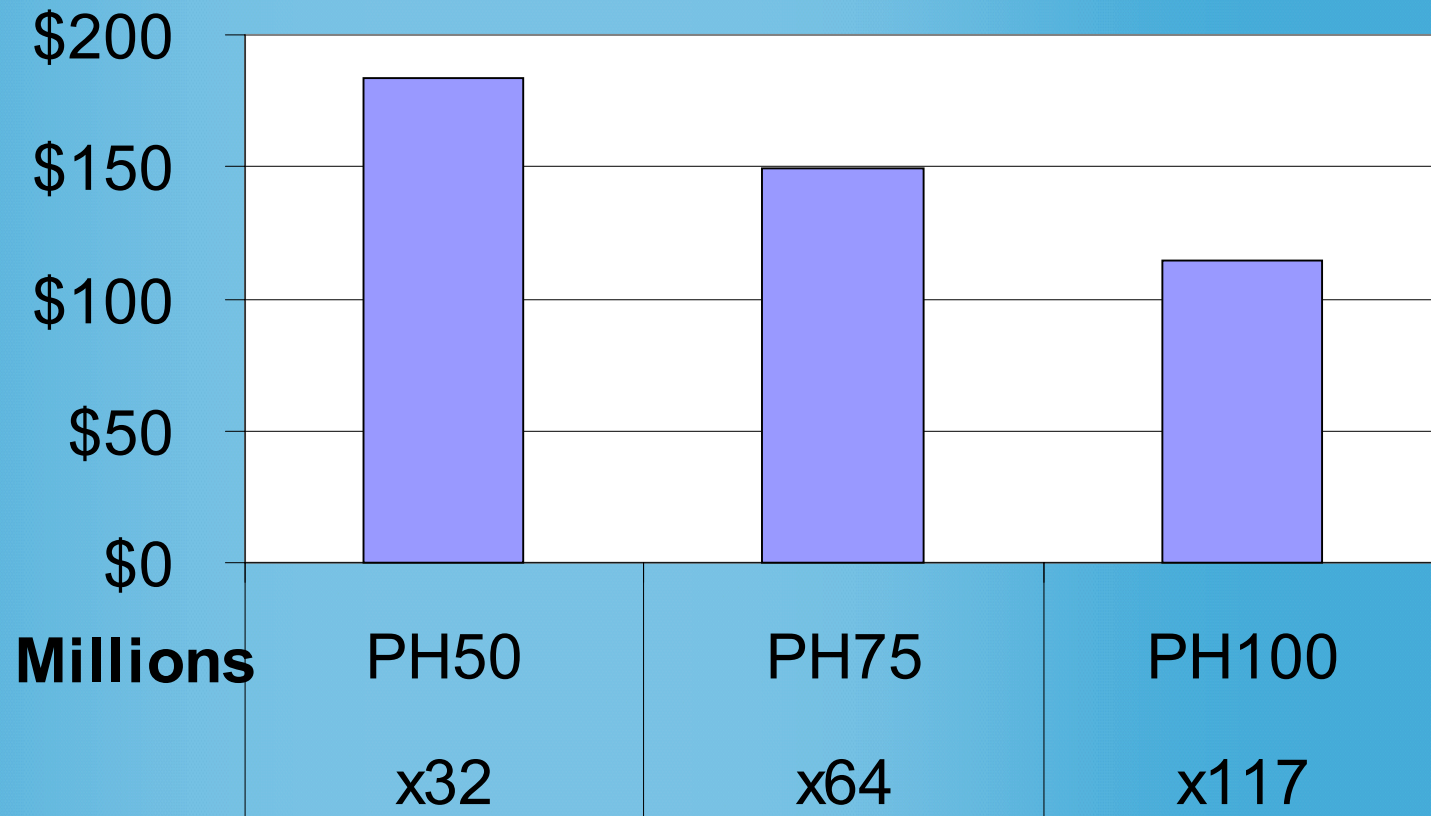
Total Test Cost per Good Die



High Parallelism Probing

- Delivers Overall Cost Savings

5 Year Test Cell Equipment Costs



PH100 - 4 Touchdown Solution:

Spring Technology and Active Area:

- T1 - 105 mm x 110 mm
- T2.1 – 112 mm array diagonal
- Planarity < 38 microns across array
- Both support:
 - Lead on center and edge pad designs
 - Odd # of rows and columns

PH100 - 4 Touchdown Solution:

Probe Head:

- Multilayer ceramic
- 7544 I/O resources
- Supports maximum resources of Probe One and T5375
- x128 test parallelism possible

MicroSpring™ Test Interface System

Controlled impedance PCB

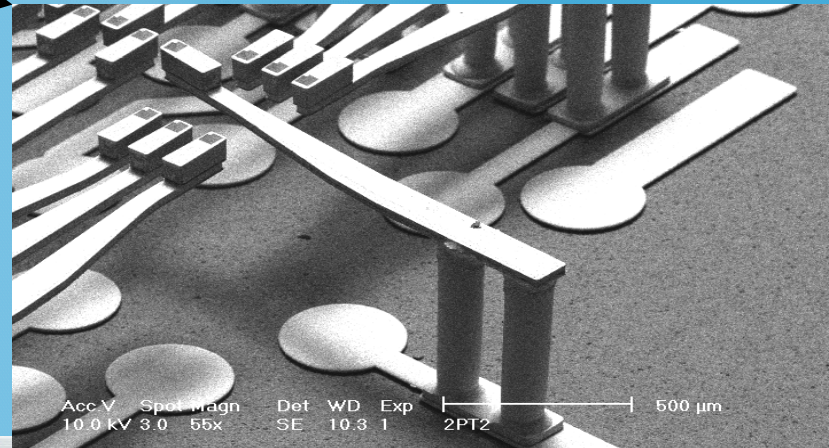
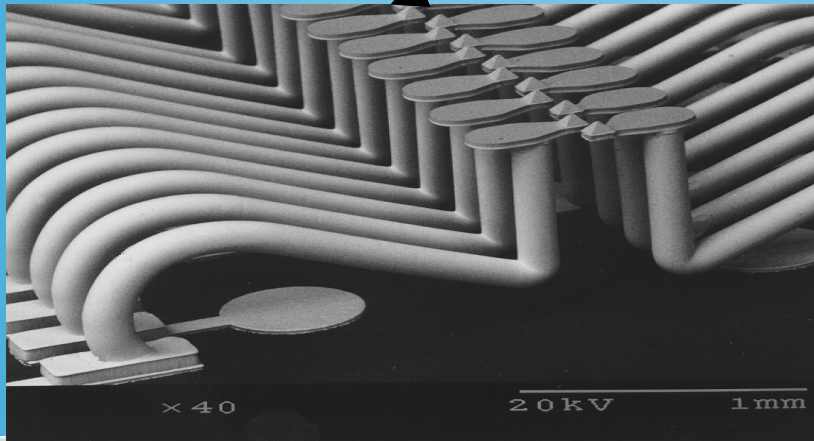
Planarizers

Resilient
Microspring
Interposer

Space transformer
with Microspring™
probes

T1 Probe Array

T2.1 Probe Array

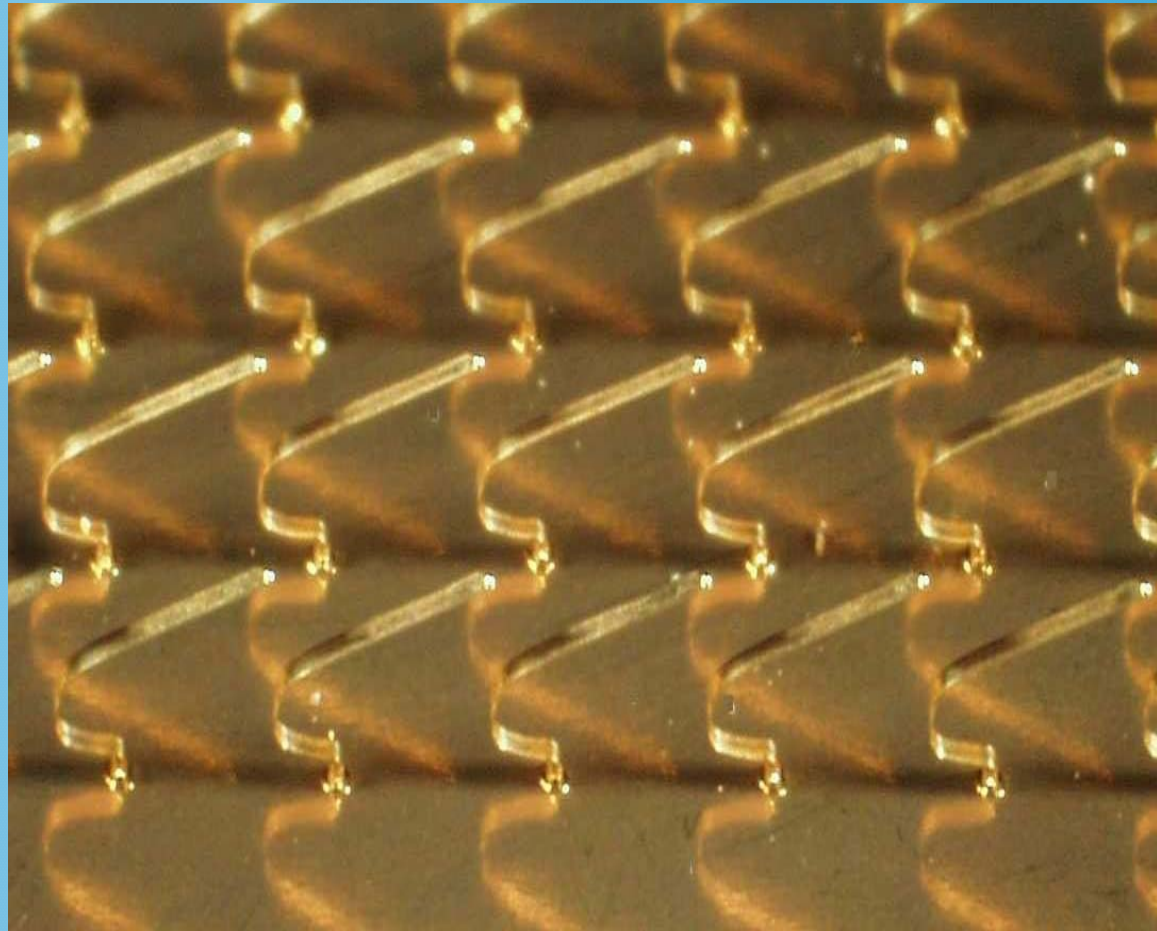


MicroSpring™ Interposer

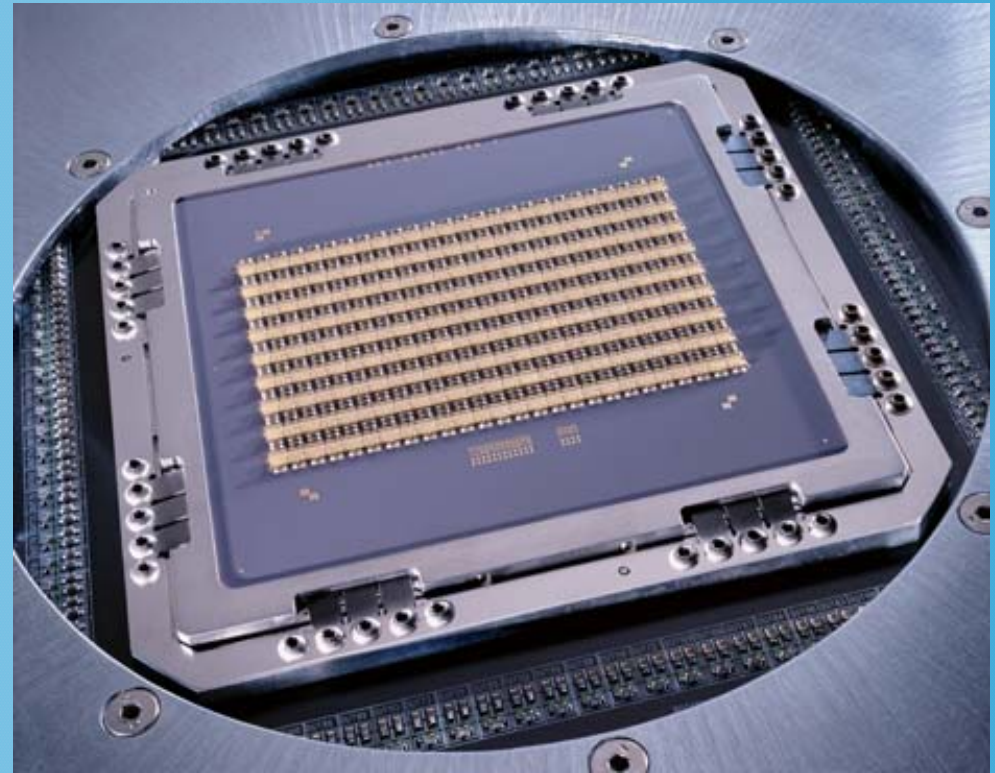
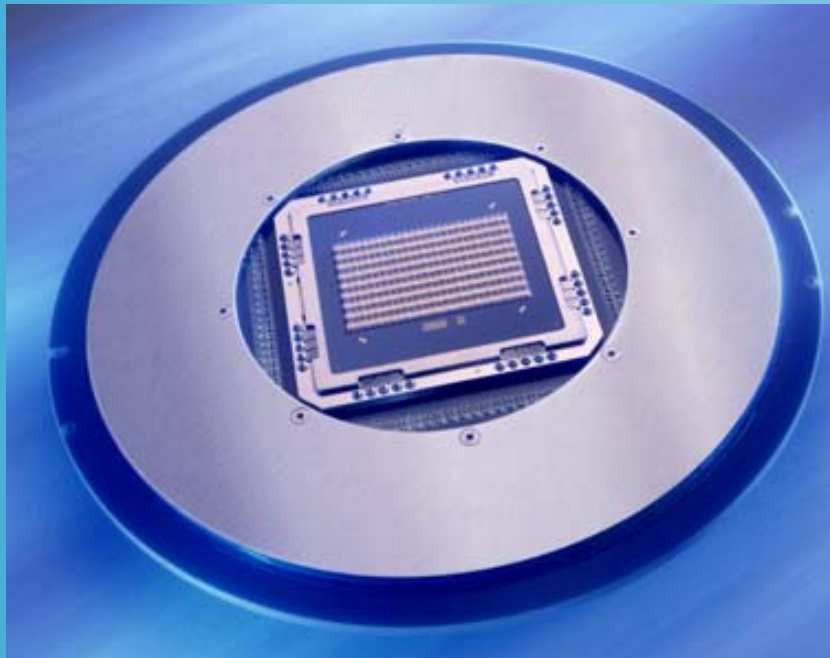
Printed circuit
board to ceramic
interface

Wide range of
compliance

Capable of 15 mil
adjustment range



PH100 - 117 DUTs, 128M SDRAM



MicroSpring™ Array Performance

Measured on the API PRVX₂

Electrical Performance -C(res)

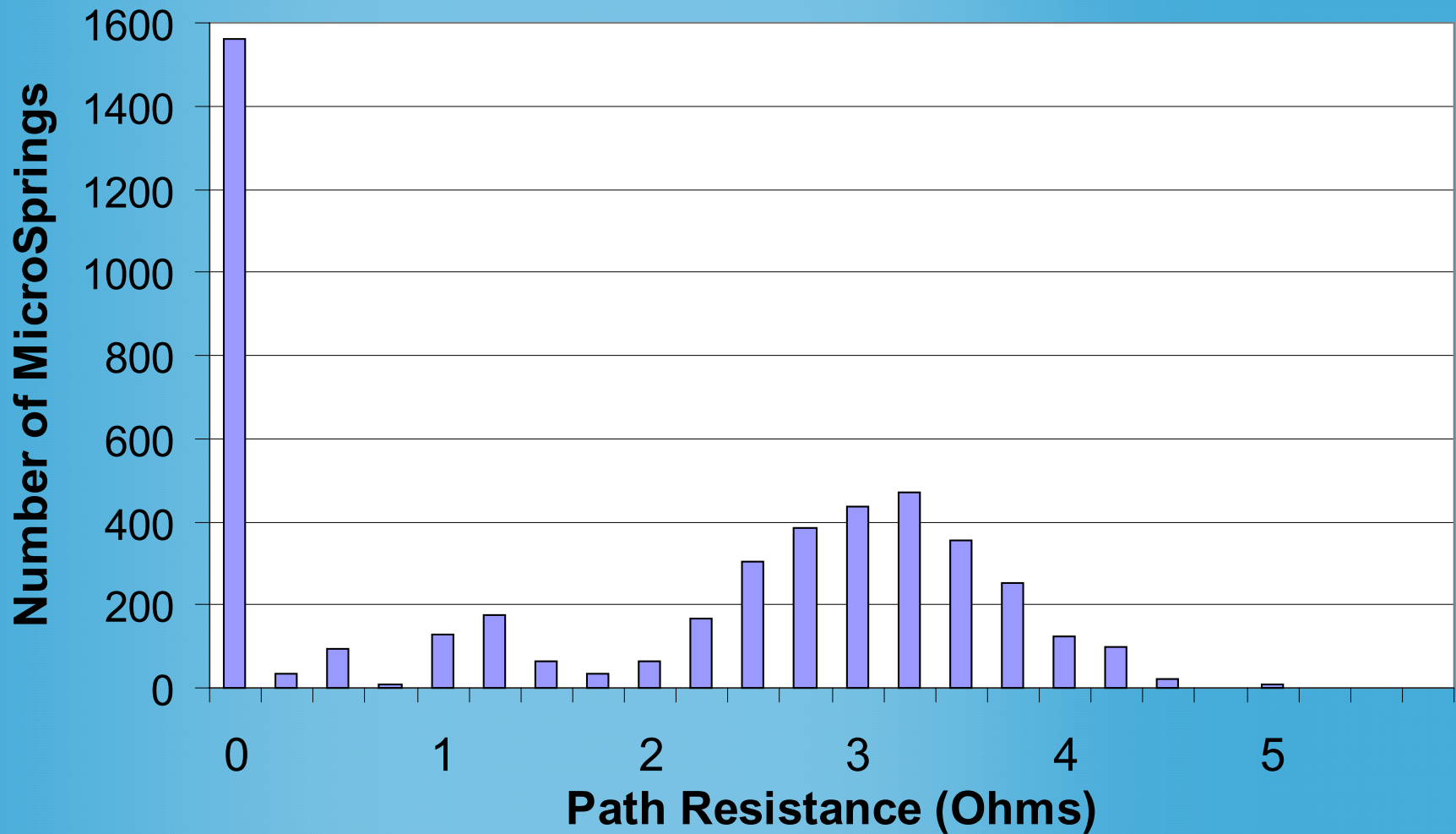
Alignment and planarity of x117 array

Scrub Mark Verification on API wafer WoRx

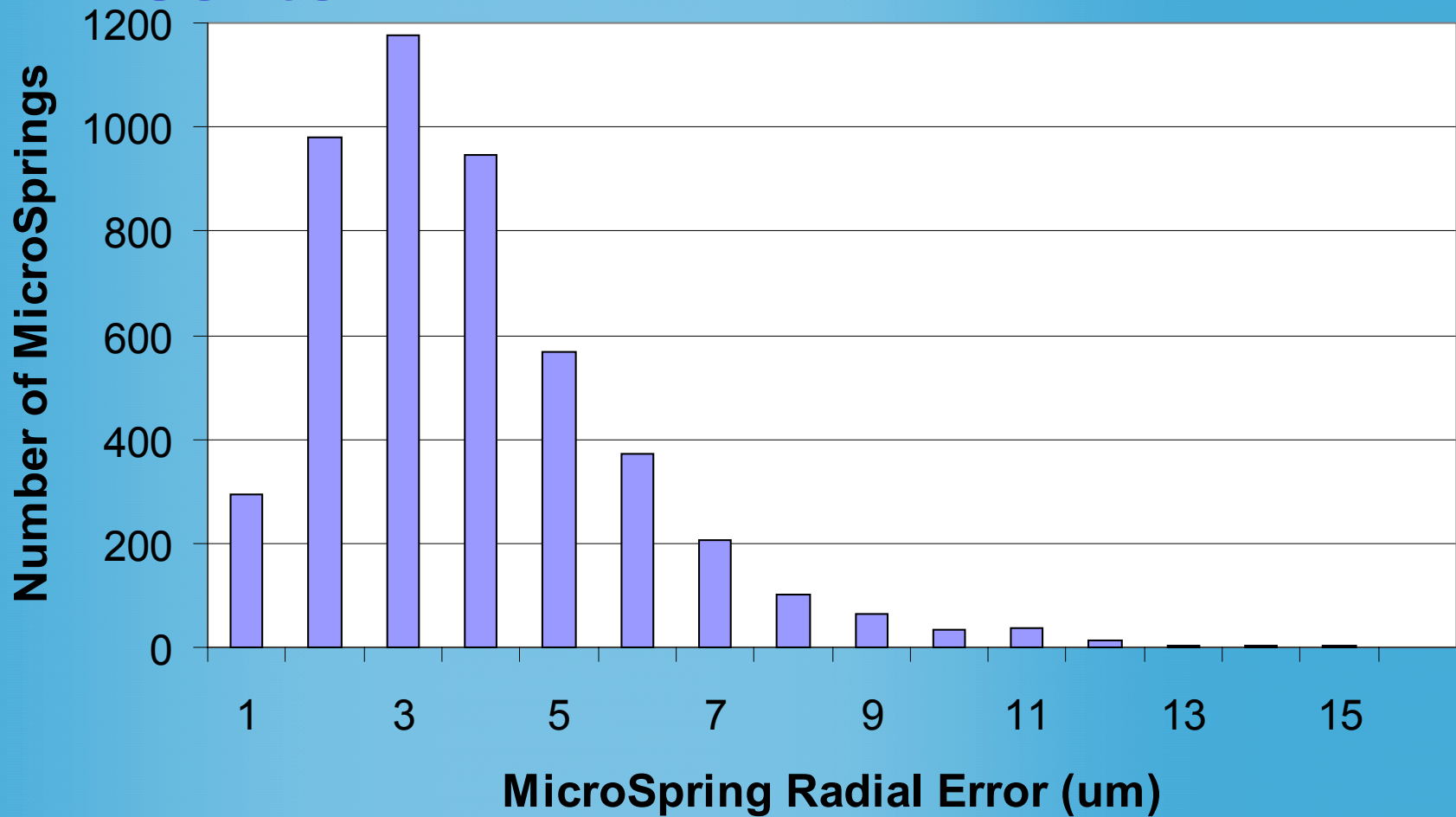
Alignment across array at 25 and 88C

4797 MicroSprings were measured on API PRVX₂

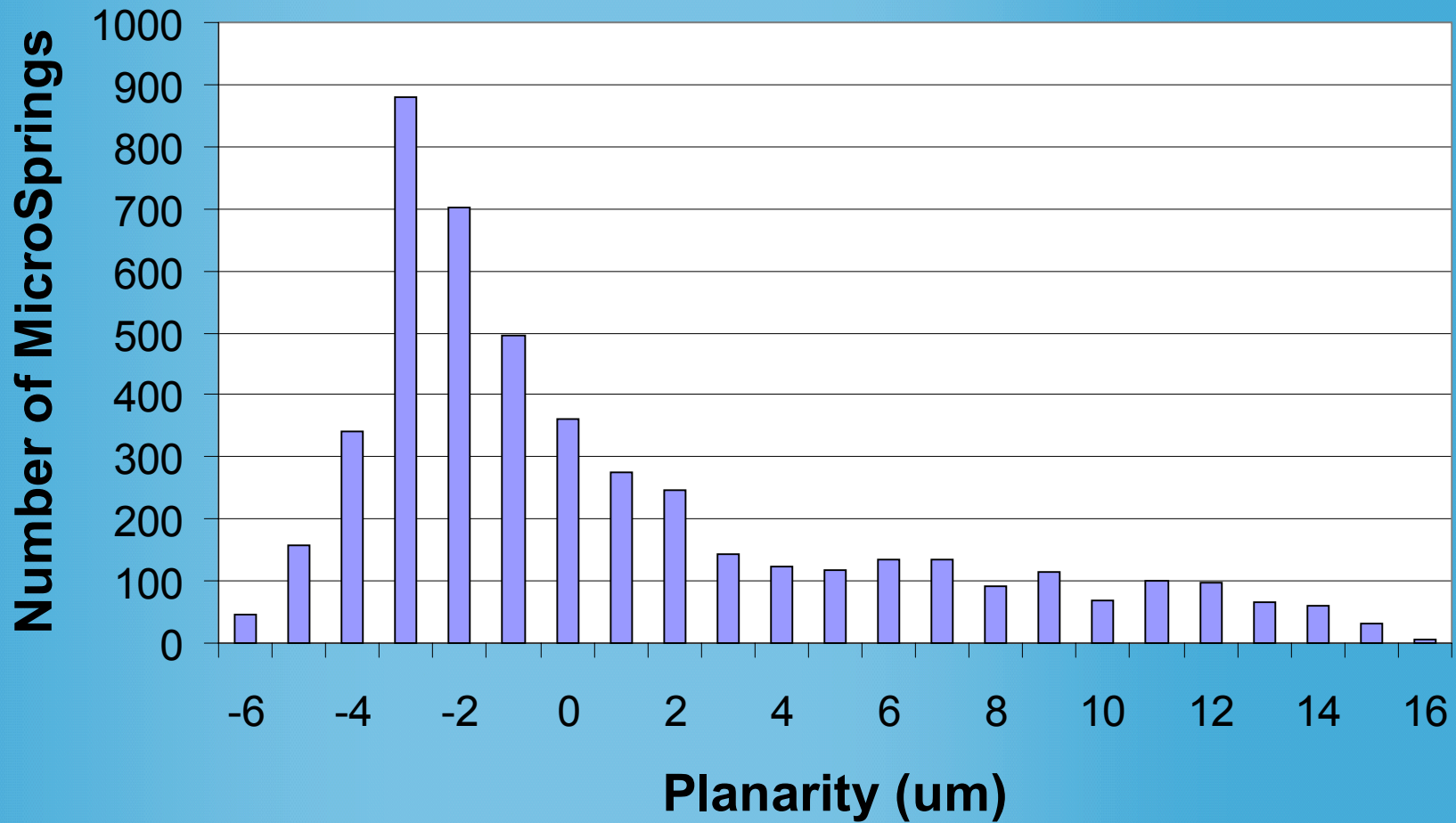
PH100 Path Resistance



PH100 Alignment Error from Pad Center



PH100 Planarity



Scrub Alignment vs. Temperature

Scrub mark alignment

Distance from center of pad to center of scrub

API waferWorx:

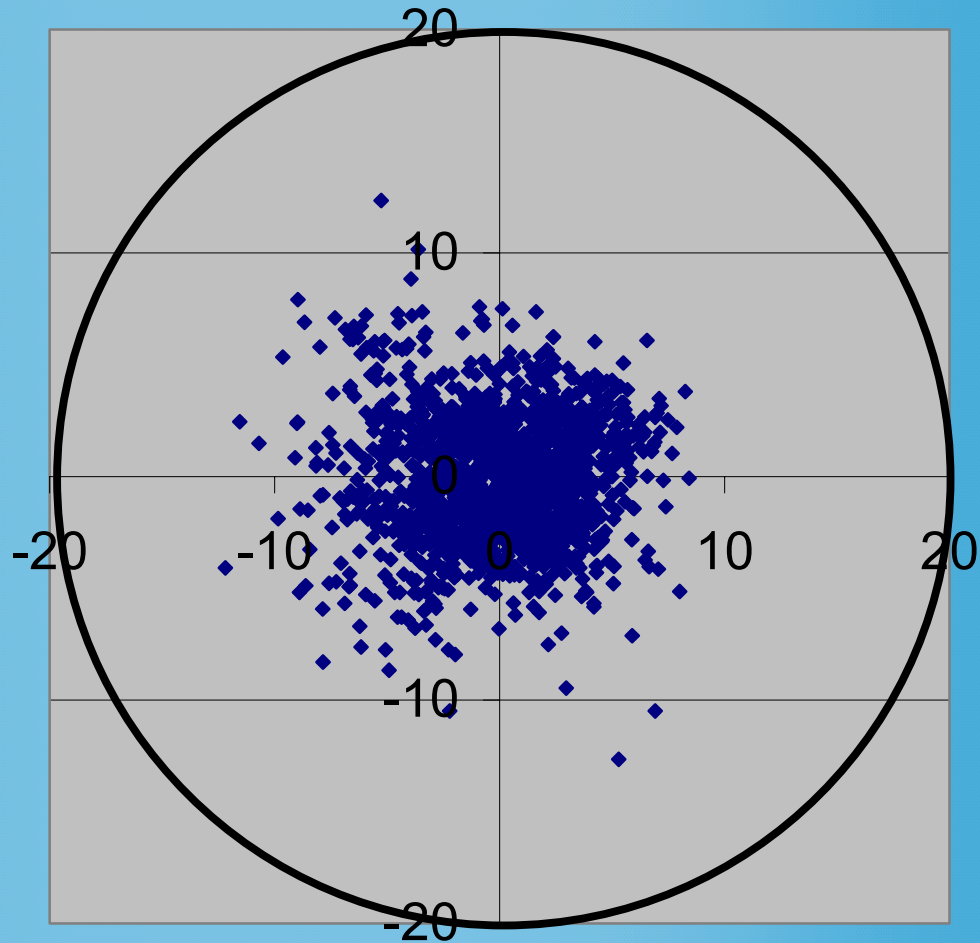
1170 Duts x 42 pads/DUT = 49,140 scrub marks

3 wafers probed at 25°C and 88°C

Delta scrub alignment 25°C vs. 88°C

Scrub Alignment at 25°C

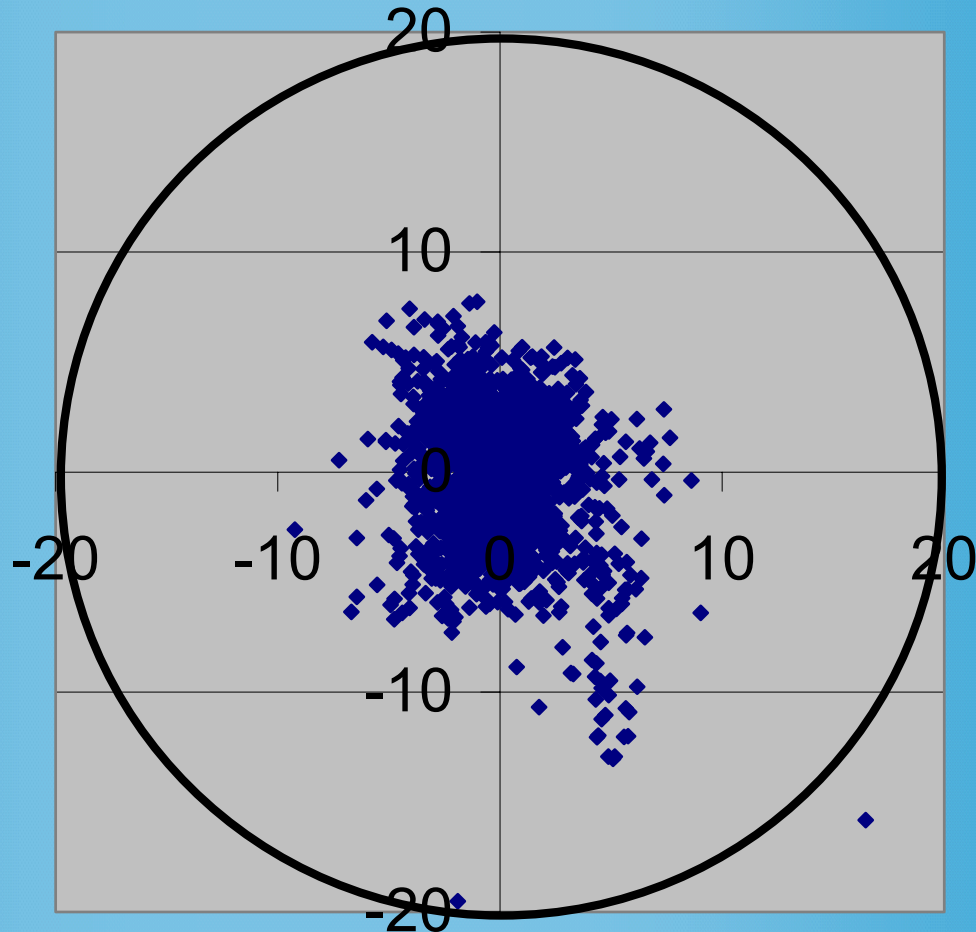
Scrub Position at Ambient - Prober Error Removed



*waferWORX*TM

Scrub Alignment at 88°C

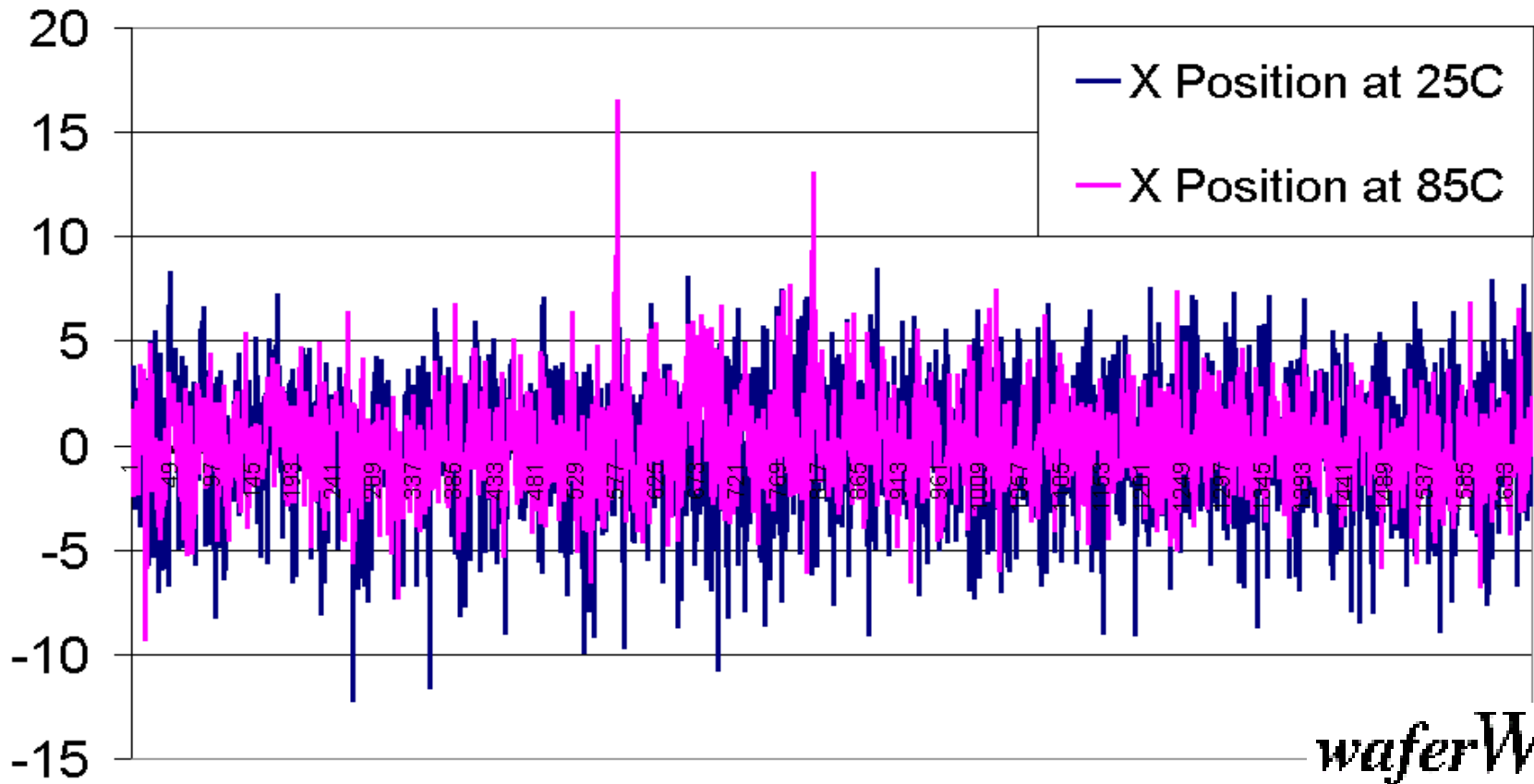
Scrub Position at 88C - Prober Error Removed



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Delta Scrub Alignment 25°C to 88°C

X Position from Pad Center



waferWoRx™

Summary and Conclusions

Increases in parallelism significantly reduce overall cost of test

MicroSpring™ technology is capable of supporting large, high pin count, array areas

FormFactor's PH100 will support the next generation of high parallelism probe arrays while maintaining stability over time and temperature

Special Thanks

Alec Gomez – Teradyne

Touchdowns on x117 PC

John Strom – API

WaferWorx analysis

Chris Buckholtz – FormFactor

Experiment support